not limited to the shape illustrated in FIGS. 1 and 2. For example, the present invention can be applied to probes having three or more arm members 3.

[0038]

[First modified example]

Next, a first modified example will be described. FIG. 8 is a perspective view of a probe 100A according to the first modified example, and FIG. 9 is a side view of the probe 100A. The probe 100A illustrated in FIGS. 8 and 9 differs from the probe 100 illustrated in FIGS. 1 and 2 in that the contact portion 6 and the projection 5A are coupled to each other.

[0039]

As described above, the contact portion 6 and the projection 5A are made of the same material, for example, Rh. Therefore, the contact portion 6 and the projection 5A can be formed at once by photolithography, thereby reducing labor and cost during manufacture.

[0040]

[Second modified example]

FIG. 10 is a side view of a probe 100B according to a second modified example. In the probe 100B illustrated in FIG. 10, the projection 5A formed on the outer edge portion 4a of the tip member 4 is formed shorter than that of the probe 100 illustrated in FIG. 2. Even in this configuration, as in the first embodiment described above, it is possible to accurately position the probe 100B even when the guide plates 21 and 22 with the openings 31 and 32 having arc-shaped corner portions are used. In addition, it is possible to reduce the material for forming the projection 5A, thereby reducing the cost.

[0041]

[Third modified example]

FIG. 11 is a side view of the probe 100C according to a third modified example. In the probe 100C illustrated in FIG. 11, the projection 5B formed on the outer edge portion 2a of the support member 2 is formed intermittently in comparison with the probe 100 illustrated in FIG. 2. Even in this configuration, as in the first embodiment described above, it is possible to accurately position the probe 100C even when the guide plates 21